ESCAPE

Burn/Wet System

ESCAPE is our best-known abatement system for the semiconductor and photovoltaic industries.

The **ESCAPE** technology offers an optimum combination of the two operating procedures burning & scrubbing in the smallest possible space. It is an effective and highly versatile technology for waste gas abatement with low cost of ownership. Based on this technology we have developed the ESCAPE product line, which offers flexible and customized applications for the abatement of almost all process waste gases in the semiconductor and photovoltaic industries. All ESCAPE systems have a small footprint with service and maintenance access from the front and back. Installation is quick and easy and does not require specialized equipment. Cost of operation can be optimized with a process-tool-interface.

It abates gas flows of up to 300 slm*. As an alternative to the scrubber liquid's feedthrough-system the reactor can be equipped with a water-conserving closed-loop design.

ESCAPE DUO is a dual system with two reactor and scrubbing systems that can work simultaneously.

It treats waste gas flows of up to 300 slm* per reactor from various processes, lead in through a maximum of 2+2 independent inlets, and runs on diverse fuel gases and scrubber liquids. The abatement system is equipped with a water-conserving closed-loop scrubbing design. In case of malfunction or maintenance on one reactor, the other backs up the treatment of all waste gases (internal backup), which ensures the equipment's uptime of nearly 100 %.

*) average values, depending on process

Basic Features

- Power Supply:
  3 x 400 V/50 Hz or 3 x 208 V/60 Hz
- Fuel Gas: NG, LPG, H_2
- Oxidant: O_2
- Circulation with water or lye
- Process-Tool-Interface
- Signal Tower
- Drip Pan
- Earthquake Safety Kit
- Ethernet Interface
- SEMI S2 Certification
- Customized wastewater treatment solution available

Dual System **ESCAPE *DUO***

DAS
Environmental Experts.

ESCAPE

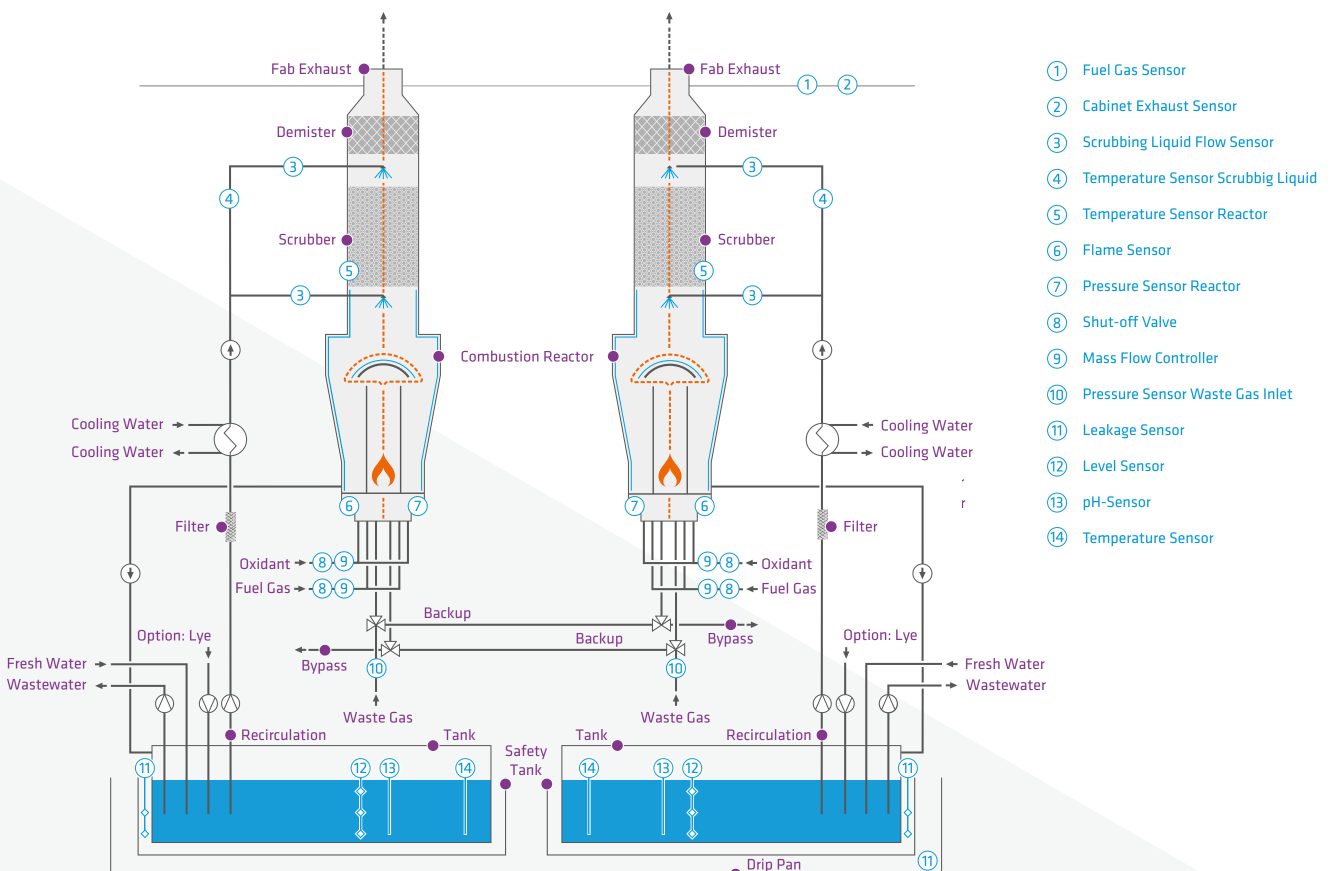
Burn/Wet System

Technical Data

	ESCAPE *DUO*
Measurements (WxDxH) in mm	1650 x 675 x 1800/2070
Max. Inert Gas Flow in m^3/h	18
Max. Gas Entry	2 x 2 x DN 25 or DN 40
Gas Outlet	2 x DN 100
Interal back-up function	✓

System Description

Hazardous substances of process waste gases are abated directly at their place of origin (Point-of-Use, POU). Waste gases are fed into a ring-shaped burner apparatus. Depending on the chemical composition of the waste gases, various reactions take place (oxidation, reduction, pyrolysis). In the subsequent scrubbing process, soluble, gaseous and solid compounds generated by combustion are absorbed and cooled down by a suitable scrubbing liquid. The immediate scrubbing neutralizes combustion products such as hydrogen halides, and all remaining residual gases meet the standards of the German air pollution law (TA Luft).



Operation Principle **ESCAPE *DUO***